

MEMs Parallel Plate Rheometer for Oscillatory Shear Micro Rheology Measurements

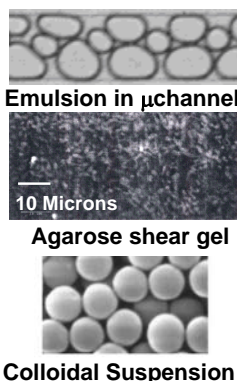
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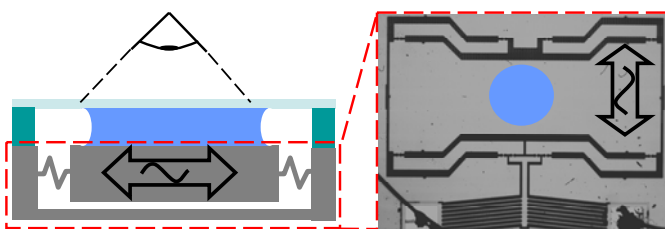
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Motivation

- Novel viscoelastic materials
 - Micro scale structure
- Confinement deforms structure
 - Alters rheology
- Characterization difficult
 - Small sample volumes
- Particle micro rheology does not probe entire micro structure
- Thin film measurements only elastic modulus



MEMs Parallel Plate Rheometer



- 1 mm² **nano-positioner** applies sinusoidal strain
 - Thermal Actuator
 - 0.1% < γ < 25%
- O(1) μ m gap set with **thin film**
- Strain applied to the entire fluid body
- Optical observation
- Storage and loss moduli at 0.5 Hz < f < 500 Hz
- Uses less than **10 nL of fluid**

Mechanical Modeling

• Fluid modeled as Voigt Element

- X_s **nano-positioner** motion
- X_a actuator motion

$$\frac{m_s}{k_s} \ddot{x}_s + \frac{\eta}{k_s} \dot{x}_s + \left(2 + \frac{G}{k_s}\right) x_s = x_a$$

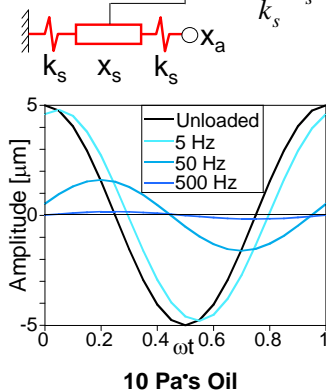
$$\frac{x_{s,loaded}}{|x_{s,unloaded}|} = |x| \sin(\omega t + \phi)$$

$$\frac{2k_s - \omega^2 m_s}{|x|}$$

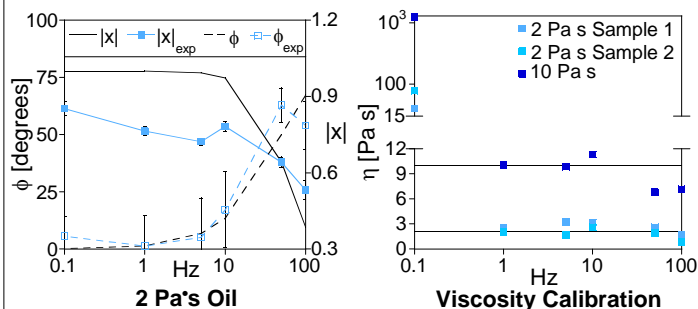
$$\omega \eta$$

$$\phi$$

$$G + 2k_s - \omega^2 m_s$$

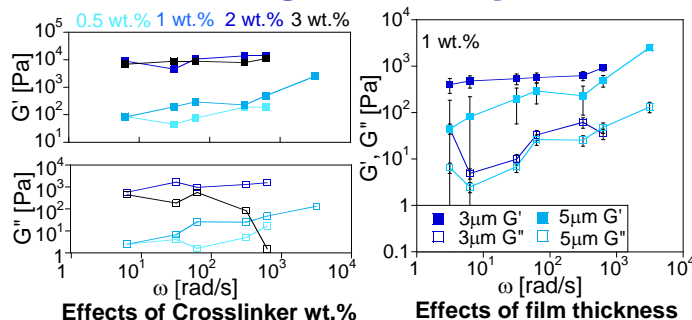


Viscous Fluid Calibration

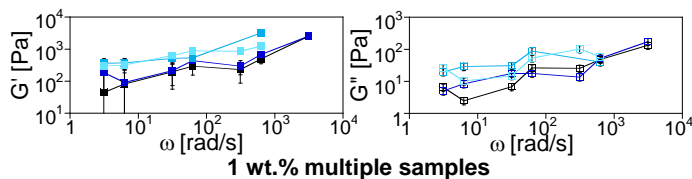


- Surface tension affects amplitude
- Model predicts general behavior
- $\pm 25\%$ device error on viscosity above 1 Hz
- ± 150 Pa error on elastic modulus above 1 Hz

PDMS Thin Films



- Moduli grow with increasing wt. %
 - 3 wt. % G' consistent with DMA
 - G' larger for thinner film
 - Trends consistent with observed behavior
- Chen et al., J. Micromech. Microeng. (2009)
Chang et al., J. Polym. Sci. B (2005)



Conclusions

- MEMs Rheometer with optical analysis can extract rheology
 - Model matches observed phenomenon
 - Consistent results for viscous fluids and viscoelastic thin films
 - Large frequency domain, ~ 3 decades, with O(1) μ m gap sizes
 - Redesign of device should improve accuracy and sensitivity
- 5 μ m Gap, High MW PIB in 500 g/mol PIB oligomer